Transaction Information

Tool ID	DFRN716
Tool Status	Running Wafers
Location	Singapore
Wafer Size	300 mm
Fab Section	Diffusion
Tool Available Date	2025-03-31

General Product Information

Vendor Supplier	TEL	
Model	TEL FORMULA-1S-H	
Vintage	2008	
Serial No	P000008X5073	
Asset Description	LPCVD Nitride with In-situ clean furnace	
Software Version	V2.12 Rev.R010 [F00B00-0000F]	
СІМ	SECS	
Process	LPCVD Nitride with In-situ clean	

Hardware Configuration

System Type	Description	Quantity	Status
Factory Interface	FOUP	2	ОК
Options System	RCU	1	ОК
Others	Gas detector	1	ОК
Main System	TEL Formula Nitride furnace	1	ОК
Handler System	TEL Formula Robot		ОК
Others	Power Box		ОК

Excluded Items List (Pumps, Chillers & Abatement are all excluded)

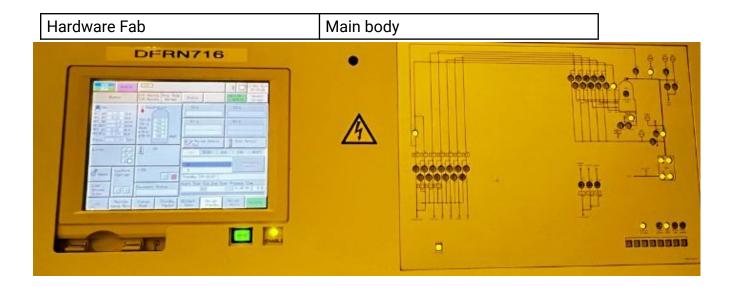
Description	Quantity
Nil	

* List above may or may not be comprehensive. Tool is sold in "as-is" condition. To ensure your satisfaction, we strongly recommend to make an appointment to inspect this and every tool you are interested in.

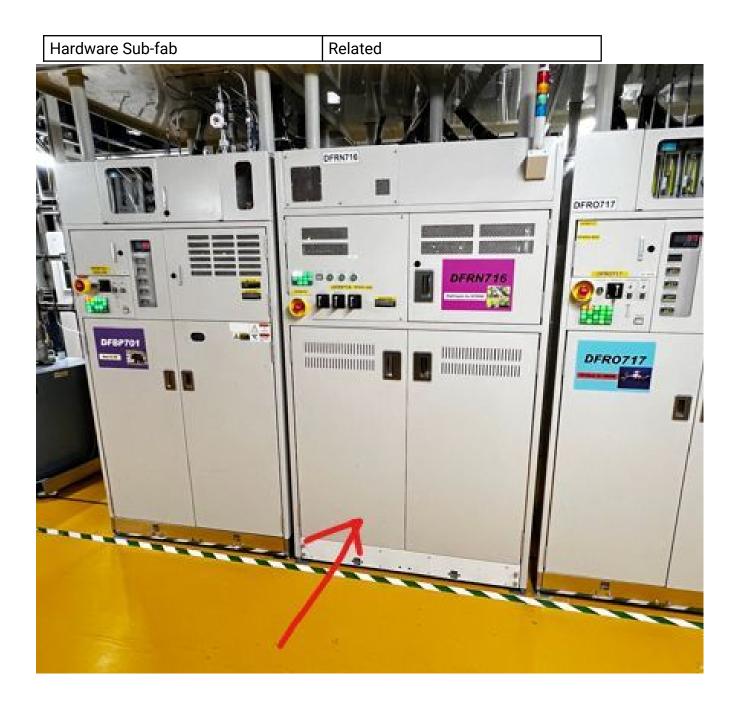
Tool Pictures













Manufacture Serial	P000008X5073	
ТҮРЕ	EE03	
SERIAL NO.		
ELECTRICAL DIAGR	AM, NO.	
DATE OF MANOPA	TORED .	
Ο ΤΟΚΥΟ Ε	ELECTRON LIMI	TED JAPAN